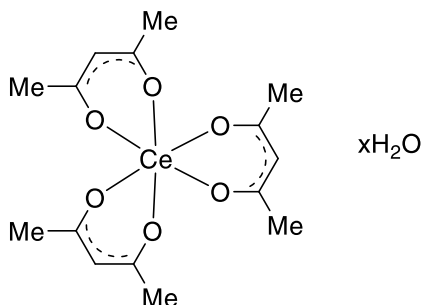


Catalog # 93-5802 Cerium(III) acetylacetonate hydrate (99.9%-Ce) (REO)



Thermal Behavior:

- TGA curves and data available in [1, 3]

Technical Notes:

1. MOCVD, ALD precursor for preparation of cerium oxide thin films.

Target Deposit	Deposition Technique	Delivery Temperature	Pressure	Co-reactants	Deposition Temperature	Ref.
MgO-CeO ₂	MOCVD	109-240°C	AP	Mg(acac) ₂ , O ₂	470-570°C	1
ZnO-CeO ₂	MOCVD	130°C	AP	Zn(acac) ₂ , O ₂	400-700°C	2-3
CeO ₂	MOCVD	60-250°C	AP	Ar, Air	300-900°C	4

References:

1. [ECS Trans., 2009, 20, 447.](#)
2. [ECS Trans., 2009, 25, 467.](#)
3. [J. Solid State Chem., 2010, 183, 2205.](#)
4. [Mat. Lett., 2017, 204, 39.](#)